•

Sheet

ア・ブ

Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

of

US-6,700,134 B2

Application Number	10/813,233		
Filing Date	March 31, 2004		
First Named Inventor	Shunpei YAMAZAKI et al.		
Art Unit	2823		
Examiner Name	Trung Q. Dang		
	Filing Date First Named Inventor Art Unit		

Complete if Known

740756-2719 U.S. PATENT DOCUMENTS U.S. Patent Document Publication Date MM-DD-YYYY Name of Patentoe or Applicant of Cited Document toitials* Pages, Columns, Lines, Where Relevant Number - Kind Code (if known) Passages or Relevant Figures Appear US-5,430,320 07-04-1995 US-5,594,569 01-14-1997 Konuma et al. US-5,619,044 04-08-1997 MAKITA et al. US-5,812,137 09-22-1998 KERKER, JR. et al. 12-22-1998 US-5,851,860 MAKITA et al. US-5,917,564 06-29-1999 KIM et al. US-6,017,779 01-25-2000 **MIYASAKA** US-6,124,155 09-26-2000 ZHANG et al. US-6,140,668 10-31-2000 MEI et al. US-6,143,661 11-07-2000 KOUSAI et al. US-6,144,082 11-07-2000 YAMAZAKI et al. US-6,144,426 11-07-2000 YAMAZAKI et al. US-6,146,927 11-14-2000 YAMANAKA et al. US-6,160,268 12-12-2000 YAMAZAKI et al. US-6,177,302 B1 01-23-2001 YAMAZAKI et al. US-6,261,877 B1 07-17-2001 YAMAZAKI et al. 07-17-2001 US-6,261,881 B1 YAMAZAKI et al. US-6,348,369 B1 02-19-2002 KUSUMOTO et al. US-6,380,011 B1 04-30-2002 YAMAZAKI et al. US-2002/0072157 06-13-2002 JINNO et al. US-6,410,961 B1 06-25-2002 HAYASHI US-6,462,798 B1 KIM et al. 10-08-2002 US-6,482,752 B1 11-19-2002 YAMAZAKI et al. US-2003/0027380 A1 02-06-2003 YAMAZAKI US-6,555,422 B1 04-29-2003 YAMAZAKI et al.

Attorney Docket Number

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS				
Examiner Initials	Cite No.1			
T.D		H. HAYASHI et al., "Fabrication of Low-Temperature Bottom-Gate Poly-Si TFTs on Large-Area Substrate by Linear-Beam Excimer Laser Crystallization and Ion Doping Method", IEDM 95: Technical Digest of International Electronic Devices Meeting, 1995 IEEE, pgs. 33.3.1-4 (pgs. 829-832).		

YAMAZAKI et al.

03-02-2004

Examiner	- 200//	Date	(191/05
Signature	T. 2476	Considered	1 6/24/05

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Applicant's unique citation designation number (optional). See Kinds Codes of USPTO Patent Documents at 222 uspto gov or MPEP 901.04. Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. Applicant is to place a check mark here if English language Translation is attached. W647754.2